

## **Advanced Lithography**

Instructor: Anthony Yen, TSMC

- Principles of projection imaging
- Resolution-enhancing techniques
- Scanner, mask, photoresist
- Extreme-ultraviolet lithography (EUVL)

**Anthony Yen** is Director of Nanopatterning Technology Infrastructure Division at Taiwan Semiconductor Manufacturing Company. Among his responsibilities is the development of EUV lithography. Yen received BSEE from Purdue University, SM, EE, and PhD in electrical engineering and computer science from MIT, and MBA from MIT's Sloan School of Management. He has over seventy publications and holds over thirty U.S. patents on semiconductor technology. He is a fellow of SPIE, a past chair of its Advanced Lithography symposia and several conferences on semiconductor lithography.